

Title (en)  
A bonded wafer and a method of manufacturing it

Title (de)  
Verbundenes Plättchen und dessen Herstellungsverfahren

Title (fr)  
Substrat lié et méthode de fabrication

Publication  
**EP 0444942 B1 19971008 (EN)**

Application  
**EP 91301679 A 19910228**

Priority  
JP 4577790 A 19900228

Abstract (en)  
[origin: EP0444942A1] A bonded wafer comprising a filmy bond wafer (1), a base wafer (2), and an intermediate silicon dioxide layer (3), wherein the periphery of the bond wafer (1) is etched; this bonded wafer is made by subjecting the bond wafer to an oxidation treatment to form an oxide film over it; joining the two wafers in a manner such that the oxide film-covered face of the bond wafer is put on the base wafer to thereby sandwich the oxide film between the wafers; heating the combined wafers to thereby create a bonding strength between the two wafers; grinding the exposed face of the bond; etching the periphery of the bond wafer to remove the portion which is not in contact with the base wafer; and polishing the exposed face of the bond wafer until it becomes a thin film. <IMAGE>

IPC 1-7  
**H01L 21/18**; **H01L 21/306**

IPC 8 full level  
**H01L 21/02** (2006.01); **H01L 21/20** (2006.01); **H01L 21/306** (2006.01); **H01L 21/762** (2006.01); **H01L 27/12** (2006.01)

CPC (source: EP US)  
**H01L 21/2007** (2013.01 - EP US); **H01L 21/30604** (2013.01 - EP US); **H01L 21/76251** (2013.01 - EP US); **Y10S 148/012** (2013.01 - EP US); **Y10S 148/135** (2013.01 - EP US); **Y10S 438/978** (2013.01 - EP US); **Y10T 428/219** (2015.01 - EP US)

Citation (examination)  
EP 0413547 A2 19910220 - SHINETSU HANDOTAI KK [JP]

Cited by  
EP0935280A1; EP0856876A3; EP1845557A3; EP0628995A1; EP0860862A3; EP1170801A4; US8298916B2; US7718507B2; US8429960B2; US6417108B1; US7245002B2; US8679944B2; US9138980B2; US8338266B2; US8871611B2

Designated contracting state (EPC)  
DE FR GB

DOCDB simple family (publication)  
**EP 0444942 A1 19910904**; **EP 0444942 B1 19971008**; DE 69127841 D1 19971113; DE 69127841 T2 19980326; JP H03250616 A 19911108; JP H0719737 B2 19950306; US 5340435 A 19940823

DOCDB simple family (application)  
**EP 91301679 A 19910228**; DE 69127841 T 19910228; JP 4577790 A 19900228; US 94493 A 19930105